

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

|                                |   |                         |
|--------------------------------|---|-------------------------|
| In re Application of:          | § |                         |
| Yau, et al.                    | § |                         |
|                                | § | Group Art Unit: Unknown |
| Serial No.: Unknown            | § |                         |
|                                | § |                         |
| Confirmation No.: Unknown      | § |                         |
|                                | § | Examiner: Unknown       |
| Filed: HEREWITH                | § |                         |
|                                | § |                         |
| For: A Low Dielectric Constant | § |                         |
| Film Produced From Silicon     | § |                         |
| Compounds Comprising           | § |                         |
| Silicon-Carbon Bond            | § |                         |

MAIL STOP PATENT APPLICATION  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

|   |                                      |
|---|--------------------------------------|
| CERTIFICATE UNDER 37 CFR 1.10   |                                      |
| I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on <u>1/13</u> , 2004 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. <u>EV335471697US</u> addressed to: MAIL STOP PATENT APPLICATION, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450. |                                      |
| <u>1/13/04</u><br>Date  | <u>Keith M. Tackett</u><br>Signature |

COMMENTS ON SUBMITTED REFERENCES

Applicants note that claim 1 of the instant application is within the scope of claim 1 of U.S. Patent No. 6,514,667, which is cited in the Information Disclosure Statement filed herewith. Applicants also note that the priority date of the instant application is prior to the priority date of U.S. Patent No. 6,514,667.

Applicants submit that the pending claims are patentable over the references of record and respectfully request allowance of the claims.

Respectfully submitted,

Keith M. Tackett  
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Attorney for Applicant(s)

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| <u>1/13/04</u><br>Date  | <u>Ken [Signature]</u><br>Signature |

INFORMATION DISCLOSURE STATEMENT

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

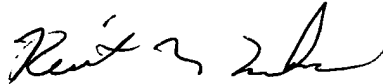
While the information submitted in this Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/2592.C7/KMT.

Respectfully submitted,



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Facsimile: (713) 623-4846  
Attorney for Applicant(s)

| U.S. Department of Commerce, Patent and Trademark Office   |     |                 |            | Docket No.                    |                 | Serial No.                   |                            |
|--|-----|-----------------|------------|-------------------------------|-----------------|------------------------------|----------------------------|
| (PTO Form 1449 modified)   |     |                 |            | AMAT/2592.C7/DSM/<br>LOW K/JW |                 | UNKNOWN                      |                            |
| LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT  |     |                 |            | Applicant<br>YAU, et al.      |                 | Confirmation No.:<br>UNKNOWN |                            |
| (Use several sheets if necessary)  |     |                 |            | Filing Date                   |                 | Group                        |                            |
| Examiner UNKNOWN   |     |                 |            | HEREWITH                      |                 | UNKNOWN                      |                            |
| <b>U.S. Patent Documents</b>   |     |                 |            |                               |                 |                              |                            |
| Examiner Initial   |     | Document Number | Issue Date | Applicant(s) Name             | Class           | Subclass                     | Filing Date If Appropriate |
|  | A1  | 6,593,655       | 07/15/2003 | Loboda, et al.                | 257             | 760                          | 08/14/2000                 |
|  | A2  | 6,514,667       | 02/04/2003 | Angelopoulos, et al.          | 430             | 271.1                        | 08/17/2001                 |
|  | A3  | 6,316,167       | 11/13/2001 | Angelopoulos, et al.          | 430             | 313                          | 01/10/2000                 |
|  | A4  | 6,287,990       | 09/11/2001 | Cheung, et al.                | 438             | 780                          | 09/29/1998                 |
|  | A5  | 6,159,871       | 12/12/2000 | Loboda, et al.                | 438             | 786                          | 05/29/1998                 |
|  | A6  | 6,147,009       | 11/14/2000 | Grill et al.                  | 438             | 780                          | 06/29/1998                 |
|  | A7  | 6,140,226       | 10/31/2000 | Grill et al                   | 438             | 637                          | 07/30/1998                 |
|  | A8  | 6,124,641       | 09/26/2000 | Matsuura                      | 257             | 759                          | 12/08/1997                 |
|  | A9  | 6,072,227       | 06/06/2000 | Yau et al.                    | 257             | 642                          | 07/13/1998                 |
|  | A10 | 6,068,884       | 05/30/2000 | Rose, et al.                  | 427             | 255.6                        | 04/28/1998                 |
|  | A11 | 6,054,379       | 04/25/2000 | Yau, et al.                   | 438             | 623                          | 02/11/1998                 |
|  | A12 | 6,054,206       | 04/25/2000 | Mountsier                     | 428             | 312.8                        | 06/22/1998                 |
|  | A13 | 6,051,321       | 04/18/2000 | Lee, et al.                   | 428             | 447                          | 10/24/1997                 |
|  | A14 | 5,989,998       | 11/23/1999 | Sugahara, et al.              | 438             | 787                          | 06/30/1997                 |
|  | A15 | 5,946,593       | 08/31/1999 | Saitoh                        | 438             | 640                          | 02/20/1996                 |
|  | A16 | 5,891,799       | 04/06/1999 | Tsui                          | 438             | 624                          | 08/18/1997                 |
|  | A17 | 5,888,593       | 03/30/1999 | Petrmichl, et al.             | 427             | 563                          | 04/12/1996                 |
|  | A18 | 5,874,367       | 02/23/1999 | Dobson                        | 438             | 787                          | 06/30/1993                 |
|  | A19 | 5,858,880       | 01/12/1999 | Dobson, et al.                | 438             | 758                          | 01/05/1996                 |
|  | A20 | 5,834,162       | 11/10/1998 | Malba                         | 430             | 317                          | 10/28/1996                 |
|  | A21 | 5,821,168       | 10/13/1998 | Jain                          | 438             | 692                          | 07/16/1997                 |
|  | A22 | 5,817,572       | 10/06/1998 | Chiang, et al.                | 438             | 624                          | 12/18/1996                 |
|  | A23 | 5,807,785       | 09/15/1998 | Ravi                          | 438             | 624                          | 08/02/1996                 |
|  | A24 | 5,800,877       | 09/01/1998 | Maeda, et al.                 | 427             | 535                          | 08/09/1996                 |
|  | A25 | 5,739,579       | 04/14/1998 | Chiang, et al.                | 257             | 635                          | 09/10/1996                 |
|  | A26 | 5,753,364       | 05/19/1998 | Rutherford, et al.            | 428             | 355R                         | 01/30/1997                 |
|  | A27 | 5,789,319       | 08/04/1998 | Havemann, et al.              | 438             | 668                          | 02/26/1996                 |
|  | A28 | 5,703,404       | 12/30/1997 | Matsuura                      | 257             | 758                          | 12/24/1996                 |
|  | A29 | 5,700,720       | 12/23/1997 | Hashimoto                     | 438             | 622                          | 12/20/1995                 |
| Examiner   |     |                 |            |                               | Date Considered |                              |                            |
| <p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p> |     |                 |            |                               |                 |                              |                            |

|   |     |                 |            |                    |                               |          |                              |  |
|---|-----|-----------------|------------|--------------------|-------------------------------|----------|------------------------------|--|
| U.S. Department of Commerce, Patent and Trademark Office  |     |                 |            |                    | Docket No.                    |          | Serial No.                   |  |
| (PTO Form 1449 modified)  |     |                 |            |                    | AMAT/2592.C7/DSM/<br>LOW K/JW |          | UNKNOWN                      |  |
| LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT   |     |                 |            |                    | Applicant<br>YAU, et al.      |          | Confirmation No.:<br>UNKNOWN |  |
| (Use several sheets if necessary)   |     |                 |            |                    | Filing Date                   |          | Group                        |  |
| Examiner UNKNOWN  |     |                 |            |                    | HEREWITH                      |          | UNKNOWN                      |  |
| U.S. Patent Documents   |     |                 |            |                    |                               |          |                              |  |
| Examiner Initial  |     | Document Number | Issue Date | Applicant(s) Name  | Class                         | Subclass | Filing Date If Appropriate   |  |
|   | A30 | 5,698,901       | 12/16/1997 | Endo               | 257                           | 758      | 09/12/1995                   |  |
|   | A31 | 5,693,563       | 12/02/1997 | Teong              | 438                           | 627      | 07/15/1996                   |  |
|   | A32 | 5,683,940       | 11/04/1997 | Yahiro             | 438                           | 760      | 12/20/1995                   |  |
|   | A33 | 5,679,413       | 10/21/1997 | Petrmichl, et al.  | 427                           | 534      | 10/11/1996                   |  |
|   | A34 | 5,638,251       | 06/10/1997 | Goel, et al.       | 361                           | 313      | 10/03/1995                   |  |
|   | A35 | 5,637,351       | 06/10/1997 | O'Neal, et al.     | 427                           | 255.37   | 05/11/1995                   |  |
|   | A36 | 5,618,619       | 04/08/1997 | Petrmichl, et al.  | 428                           | 334      | 03/03/1994                   |  |
|   | A37 | 5,616,369       | 04/01/1997 | Williams, et al.   | 427                           | 536      | 06/24/1994                   |  |
|   | A38 | 5,599,740       | 02/04/1997 | Jang, et al.       | 437                           | 190      | 11/16/1995                   |  |
|   | A39 | 5,598,027       | 01/28/1997 | Matsuura           | 257                           | 635      | 12/21/1995                   |  |
|   | A40 | 5,593,741       | 01/14/1997 | Ikeda              | 427                           | 579      | 06/28/1995                   |  |
|   | A41 | 5,578,523       | 11/16/1996 | Fiordalice, et al. | 438                           | 633      | 05/18/1995                   |  |
|   | A42 | 5,563,105       | 10/08/1996 | Dubuzinsky, et al. | 438                           | 784      | 09/09/1994                   |  |
|   | A43 | 5,559,367       | 09/24/1996 | Cohen, et al.      | 257                           | 77       | 07/12/1994                   |  |
|   | A44 | 5,554,570       | 09/10/1996 | Maeda, et al.      | 438                           | 763      | 01/09/1995                   |  |
|   | A45 | 5,530,581       | 06/25/1996 | Cogan              | 359                           | 265      | 05/31/1995                   |  |
|   | A46 | 5,525,550       | 06/11/1996 | Kato               | 437                           | 238      | 11/19/1993                   |  |
|   | A47 | 5,508,368       | 04/16/1996 | Knapp, et al.      | 427                           | 534      | 03/03/1994                   |  |
|   | A48 | 5,494,712       | 02/27/1996 | Hu, et al.         | 427                           | 489      | 11/17/1994                   |  |
|   | A49 | 5,492,736       | 02/20/1996 | Laxman, et al.     | 427                           | 579      | 11/28/1994                   |  |
|   | A50 | 5,488,015       | 01/30/1996 | Haveman, et al.    | 437                           | 195      | 05/20/1994                   |  |
|   | A51 | 5,468,520       | 11/21/1995 | Williams, et al.   | 427                           | 560      | 06/24/1994                   |  |
|   | A52 | 5,465,680       | 11/14/1995 | Loboda             | 117                           | 84       | 07/01/1993                   |  |
|   | A53 | 5,364,666       | 11/15/1994 | Williams, et al.   | 427                           | 579      | 09/23/1993                   |  |
|   | A54 | 5,362,526       | 11/08/1994 | Wang, et al.       | 427                           | 573      | 01/23/1991                   |  |
|   | A55 | 5,360,646       | 11/01/1994 | Morita             | 427                           | 574      | 09/01/1993                   |  |
|   | A56 | 5,314,724       | 05/24/1994 | Tsukune, et al.    | 427                           | 489      | 08/27/1992                   |  |
|   | A57 | 5,298,587       | 03/29/1994 | Hu, et al.         | 528                           | 10       | 12/21/1992                   |  |
|   | A58 | 5,290,736       | 03/01/1994 | Sato, et al.       | 437                           | 238      | 09/24/1991                   |  |
| Examiner  |     |                 |            |                    | Date Considered               |          |                              |  |
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| LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT   |     |                 |            |                   | Applicant<br>YAU, et al.                    |          | Confirmation No.:<br>UNKNOWN        |                                     |
| (Use several sheets if necessary)   |     |                 |            |                   | Filing Date<br>HEREWITH                     |          | Group<br>UNKNOWN                    |                                     |
| Examiner UNKNOWN  |     |                 |            |                   |   |          |                                     |                                     |
| <b>U.S. Patent Documents</b>  |     |                 |            |                   |   |          |                                     |                                     |
| Examiner Initial  |     | Document Number | Issue Date | Applicant(s) Name | Class                                       | Subclass | Filing Date If Appropriate          |                                     |
|   | A59 | 5,284,730       | 02/08/1994 | Takei, et al.     | 430   | 66       | 08/06/1992                          |                                     |
|   | A60 | 5,279,867       | 01/18/1994 | Friedt, et al.    | 427   | 583      | 07/09/1992                          |                                     |
|   | A61 | 5,250,473       | 10/05/1993 | Smits             | 438   | 790      | 08/02/1991                          |                                     |
|   | A62 | 5,246,887       | 09/21/1993 | Yu                | 438   | 761      | 07/10/1991                          |                                     |
|   | A63 | 5,224,441       | 07/06/1993 | Felts, et al.     | 118   | 718      | 09/27/1991                          |                                     |
|   | A64 | 5,208,069       | 05/04/1993 | Clark, et al.     | 427   | 226      | 10/28/1991                          |                                     |
|   | A65 | 5,204,141       | 04/20/1993 | Roberts, et al.   | 427   | 255.37   | 09/18/1991                          |                                     |
|   | A66 | 5,182,000       | 01/16/1993 | Antonelli, et al. | 204   | 181.1    | 11/12/1991                          |                                     |
|   | A67 | 5,156,881       | 10/20/1992 | Okano, et al.     | 427   | 572      | 04/16/1991                          |                                     |
|   | A68 | 5,124,014       | 06/23/1992 | Foo, et al.       | 438   | 694      | 04/11/1991                          |                                     |
|   | A69 | 5,120,680       | 06/09/1992 | Foo, et al.       | 438   | 789      | 07/19/1990                          |                                     |
|   | A70 | 5,093,153       | 03/03/1992 | Brochot, et al.   | 427   | 41       | 02/07/1989                          |                                     |
|   | A71 | 5,087,959       | 02/11/1992 | Omori, et al.     | 257   | 635      | 03/02/1988                          |                                     |
|   | A72 | 5,040,046       | 08/13/1991 | Chhabra, et al.   | 257   | 635      | 10/09/1990                          |                                     |
|   | A73 | 5,028,566       | 07/02/1991 | Lagendijk         | 438   | 784      | 07/27/1990                          |                                     |
|   | A74 | 4,981,724       | 01/01/1991 | Hochberg, et al.  | 427   | 255.37   | 10/28/1977                          |                                     |
|   | A75 | 4,973,511       | 11/27/1990 | Farmer, et al.    | 428   | 216      | 12/01/1988                          |                                     |
| <b>Foreign Patent Documents</b>   |     |                 |            |                   |   |          |                                     |                                     |
| Examiner Initial  |     | Document Number | Date       | Country           | Class                                       | Subclass | Translation                         |                                     |
|   |     |                 |            |                   |   |          | YES                                 | NO                                  |
|   | B1  | 98/59089        | 12/30/1998 | WO                | C23C  | 16/30    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B2  | 00/01012        | 01/06/2000 | WO                | H01L  | 23/48    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B3  | 9-8031          | 01/10/1997 | JP                | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B4  | 0 774 533       | 05/21/1997 | EP                | C23C  | 16/40    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B5  | 0 721 019       | 07/10/1997 | EP                | H01L  | 21/316   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B6  | 196 54 737      | 07/03/1997 | DE                | H01L  | 21/31    | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B7  | 9-237785        | 09/09/1997 | JP                | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B8  | 0 711 817       | 05/15/1996 | EP                | C09D  | 183/04   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B9  | 8-222559        | 08/30/1996 | JP                | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
| Examiner  |     |                 |            |                   | Date Considered                             |          |                                     |                                     |
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|---|-----|-----------------|------------|-------------------|---|----------|-------------------------------------|-------------------------------------|
| LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT   |     |                 |            |                   | Applicant<br>YAU, et al.                    |          | Confirmation No.:<br>UNKNOWN        |                                     |
| (Use several sheets if necessary)   |     |                 |            |                   | Filing Date<br>HEREWITH                     |          | Group<br>UNKNOWN                    |                                     |
| Examiner UNKNOWN  |     |                 |            |                   |   |          |                                     |                                     |
| <b>U.S. Patent Documents</b>  |     |                 |            |                   |   |          |                                     |                                     |
| Examiner Initial  |     | Document Number | Issue Date | Applicant(s) Name | Class                                       | Subclass | Filing Date If Appropriate          |                                     |
|   | A76 | 4,900,591       | 02/13/1990 | Bennett, et al.   | 427   | 255.17   | 01/20/1988                          |                                     |
|   | A77 | 4,894,352       | 01/16/1990 | Lane, et al.      | 438   | 763      | 10/26/1988                          |                                     |
|   | A78 | 4,845,054       | 07/04/1989 | Mitchener         | 438   | 790      | 06/26/1987                          |                                     |
|   | A79 | 4,842,888       | 06/27/1989 | Haluska, et al.   | 427   | 38       | 04/07/1988                          |                                     |
|   | A80 | 4,828,880       | 05/09/1989 | Jenkins, et al.   | 427   | 167      | 12/21/1987                          |                                     |
|   | A81 | 4,824,690       | 04/25/1989 | Heinecke, et al.  | 427   | 39       | 11/03/1987                          |                                     |
|   | A82 | 4,812,325       | 03/14/1989 | Ishihara, et al.  | 427   | 69       | 10/21/1986                          |                                     |
|   | A83 | 4,798,629       | 01/17/1989 | Wood, et al.      | 106   | 287.16   | 10/22/1987                          |                                     |
|   | A84 | 4,789,648       | 12/06/1988 | Chow, et al.      | 438   | 633      | 10/28/1985                          |                                     |
|   | A85 | 4,557,946       | 12/10/1985 | Sacher, et al.    | 427   | 489      | 06/03/1983                          |                                     |
|   | A86 | 4,168,330       | 09/18/1979 | Kaganowicz        | 427   | 39       | 10/13/1977                          |                                     |
|   | A87 |                 |            |                   |   |          |                                     |                                     |
| <b>Foreign Patent Documents</b>   |     |                 |            |                   |   |          |                                     |                                     |
| Examiner Initial  |     | Document Number | Date       | Country           | Class                                       | Subclass | Translation                         |                                     |
|   |     |                 |            |                   |   |          | YES                                 | NO                                  |
|   | B10 | 8-236518        | 09/13/1996 | JP (English Abs)  | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B11 | 8-288286        | 11/01/1996 | JP (English Abs)  | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B12 | 0 743 675       | 11/20/1996 | EP                | H01L  | 21/312   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B13 | 94/01885        | 01/20/1994 | WO                | H01L  | 21/316   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B14 | 6-163521        | 06/10/1994 | JP (English Abs)  | H01L  | 21/314   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B15 | 6-168937        | 06/14/1994 | JP (English Abs)  | H01L  | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B16 | 0 522 799       | 01/13/1996 | EP                | H01L  | 21/90    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B17 | 5-267480        | 10/15/1993 | JP (English Abs)  | H01L  | 21/90    | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B18 | 0 469 926       | 02/05/1992 | EP                | C08J  | 07/06    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B19 | 92/12535        | 07/23/1992 | WO                | H01L  | 21/312   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
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| Examiner UNKNOWN  |     |                    |            |                  | HEREWITH                      |          | UNKNOWN                             |                                     |
| Foreign Patent Documents  |     |                    |            |                  |                               |          |                                     |                                     |
| Examiner<br>Initial   |     | Document<br>Number | Date       | Country          | Class                         | Subclass | Translation                         |                                     |
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|   | B23 | 59-98726           | 06/07/1984 | JP (English Abs) | H01L                          | 12/00    | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
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|   | B26 | 0 469 926 A1       | 02/5/1992  | EP               | C08J                          | 7/06     | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B27 | 0 533 129 A2       | 09/16/1992 | EP               | C23C                          | 16/40    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B28 | 2 015 983          | 03/07/1979 | GB               | C03C                          | 17/22    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B29 | 44 04 690          | 02/15/1994 | DE               | C 23 C                        | 16/22    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B30 | 2 316 535          | 08/18/1997 | GB               | H01L                          | 21/31    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B31 | 0 289 402 A1       | 11/02/1988 | EP               | C 09D                         | 1/00     | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
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|   | B33 | 99/41423           | 08/19/1999 | WO               | C23C                          | -----    | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B34 | 8-279505           | 10/22/1996 | JP               | H01L                          | 21/316   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B35 | 0 935 283          | 08/11/1999 | EP               | H01L                          | 21/312   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
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|   | B37 | 0 926 715          | 06/30/1999 | EP               | H01L                          | 21/3105  | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B38 | 9-64029            | 03/07/1997 | JP               | H01L                          | 21/316   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B39 | 9-251997           | 09/22/1997 | JP (English Abs) | H01L                          | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B40 | 9-260369           | 10/03/1997 | JP (English Abs) | H01L                          | 21/36    | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B41 | 10-242143          | 09/11/1998 | JP (English Abs) | H01L                          | 21/316   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B42 | 198 04 375         | 02/04/1998 | DE               | H01L                          | 21/312   | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B43 | 11-251293          | 09/17/1999 | JP (English Abs) | H01L                          | 21/3065  | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B44 | 99/55526           | 11/04/1999 | WO               | B32B                          | 9/04     | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B45 | 59-222659          | 12/14/1984 | JP (English Abs) | F 16 H                        | 9/18     | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B46 | 199 04 311         | 01/28/1999 | DE               | C23C                          | 16/44    | <input checked="" type="checkbox"/> | <input type="checkbox"/>            |
|   | B47 | 0 849 789          | 06/24/1998 | EP               | H01L                          | 21/768   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
|   | B48 | 0 840 365          | 05/06/1998 | EP               | H01L                          | 21/311   | <input type="checkbox"/>            | <input checked="" type="checkbox"/> |
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| <b>LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT</b>  |     | Applicant<br>YAU, et al.   | Confirmation No.:<br>UNKNOWN |
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| Examiner UNKNOWN  |     | Filing Date<br>HEREWITH   | Group<br>UNKNOWN             |
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